What is claimed is:

1. A design method of a semiconductor manufacturing apparatus comprising:

creating a program setting file storing setting information of a program necessary for executing a process with respect to the semiconductor manufacturing apparatus based on a requirement specification from a user;

creating a program installer for introducing the program into a controller of the semiconductor manufacturing apparatus from the program setting file;

operating a processing unit of the semiconductor manufacturing apparatus;

specifying a sensor corresponding to the processing unit based on the operation of the processing unit;

creating a sensor setting file storing information obtained by specifying the sensor;

comparing a content of the requirement specification and a content of the sensor setting file to confirm a consistency between the content of the requirement specification and the content of the sensor setting file; and

introducing the program into a memory of the controller by the program installer when the content of the requirement specification and the content of the sensor setting file are consistent with each other, and

wherein specifying the sensor comprises:

operating the processing unit to output sensor data from the sensor; and

specifying the sensor corresponding to the processing unit based on the output sensor data.

2. The method according to claim 1, wherein specifying the sensor comprises:

rotating a plurality of polishing tables at different rotational speeds, in a state of connecting a table torque sensor to at least one of the polishing tables in the

processing unit;

confirming the presence or absence of output of the sensor data of the table torque sensor; and

determining whether or not the table torque sensor is connected to each of the polishing tables based on the presence or absence of output of the sensor data.

3. The method according to claim 2, wherein specifying the sensor comprises:

specifying the table torque sensor corresponding to each of the polishing tables based on different sensor data of a plurality of table torque sensors output corresponding to the different rotational speeds when determining connections of the table torque sensors to the polishing tables.

4. The method according to claim 1, wherein specifying the sensor comprises:

rotating the polishing tables at different rotational speeds in a state of connecting a trigger sensor and a film thickness measurement sensor corresponding to the trigger sensor to at least one of the polishing tables in the processing unit;

confirming the presence or absence of sensor data of the film thickness measurement sensor at a timing of a trigger signal output by the trigger sensor; and

determining whether or not the film thickness measurement sensor is connected to each of the polishing tables based on the presence or absence of output of the sensor data.

5. The method according to claim 4, wherein specifying the sensor comprises:

specifying the film thickness measurement sensor corresponding to each of the polishing tables based on the sensor data of the film thickness measurement sensor at different timings of trigger signals when specifying connection of film thickness measurement sensors to the polishing tables.

6. A non-transitory computer-readable storage medium storing a program of causing a computer to execute a design method of a semiconductor manufacturing apparatus, the program causing the computer to perform operations of:

creating a program setting file storing setting information of a program necessary for executing a process with respect to the semiconductor manufacturing apparatus based on a requirement specification from a user;

creating a program installer for introducing the program necessary for executing the process into a controller of the semiconductor manufacturing apparatus from the program setting file;

operating a processing unit of the semiconductor manufacturing apparatus;

specifying a sensor corresponding to the processing unit based on the operation of the processing unit;

creating a sensor setting file storing information obtained by specifying the sensor;

comparing a content of the requirement specification and a content of the sensor setting file to confirm a consistency between the content of the requirement specification and the content of the sensor setting file; and

introducing the program necessary for executing the process into a memory of the controller by the program installer when the content of the requirement specification and the content of the sensor setting file are consistent with each other.

7. The storage medium according to claim 6, wherein causing the computer to perform the operations comprises causing the computer to perform operations of:

operating the processing unit to output sensor data from the sensor; and

specifying the sensor corresponding to the processing unit based on the output sensor data.

8. The storage medium according to claim 6, wherein causing the computer to perform the operations comprises causing the computer to perform operations of:

rotating a plurality of polishing tables at different rotational speeds, in a state of connecting a table torque sensor to at least one of the polishing tables in the processing unit;

confirming the presence or absence of output of the sensor data of the table torque sensor; and

determining whether or not the table torque sensor is connected to each of the polishing tables based on the presence or absence of output of the sensor data.

9. The storage medium according to claim 8, wherein causing the computer to perform the operations comprises causing the computer to perform operations of:

specifying the table torque sensor corresponding to each of the polishing tables based on different sensor data of a plurality of table torque sensors output according to the different rotational speeds when determining connections of the table torque sensors to the polishing tables.

10. The storage medium according to claim 6, wherein causing the computer to perform the operations comprises causing the computer to perform operations of:

rotating the polishing tables at different rotational speeds, respectively, in a state of connecting a trigger sensor and a film thickness measurement sensor corresponding to the trigger sensor to at least one of the polishing tables in the processing unit;

confirming the presence or absence of sensor data of the film thickness measurement sensor at a timing of a trigger signal output by the trigger sensor; and

determining whether or not the film thickness measurement sensor is connected to each of the polishing tables based on the presence or absence of output of the sensor data.

11. The storage medium according to claim 10, wherein causing the computer to perform the operations comprises causing the computer to perform operations of:

specifying the film thickness measurement sensor corresponding to each of the polishing tables based on the sensor data of the film thickness measurement sensor at different timings of trigger signals when specifying the connections of film thickness measurement sensors to the polishing tables.